



4619 #230  
m.m.  
9/25/02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLN. OF: FOTLAND et al. RECEIVED  
SERIAL NO.: 09/299,388 SEP 19 2002  
FILED: April 27, 1999 TECH CENTER 1600/2900  
FOR: METHOD FOR DEPOSITING PARTICLES ONTO A SUBSTRATE ...  
GROUP: 1619  
EXAMINER: FRANK I. CHOI DOCKET: MICRODOSE 99.01 CON

Assistant Commissioner for Patents  
Washington, D.C. 20231

AMENDMENT E

Dear Sir:

This Amendment is being filed in response to the Official Action mailed June 14, 2002.

Please amend the Application as follows:

IN THE CLAIMS:

Please amend claims 1, 32-34, 48, 52-57, 60, 63, 64, 66, 67 and 69-71 to read as follows:

1. (Thrice Amended) A method for depositing particles onto a dielectric substrate comprising the steps of forming an aerosol of said particles in a first region; transporting the resulting aerosol to a second region, and applying a charge on said aerosol particles in said second region, positioning said charged aerosol particles with essentially a zero velocity in a deposition zone located in said second region proximate to said dielectric substrate, and applying an alternating electric field formed in said deposition zone between a first electrode positioned in said second region and a second electrode positioned underlying and in contact with said dielectric substrate whereby to drive said charged particles from the aerosol and deposit said

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